



Microlithography NA TC Chapter Meeting Summary and Minutes

Web Conference
Tuesday, October 31, 2023
9:00 AM – 11:00 AM Pacific

TC Chapter Announcements

Next TC Chapter Meeting
TBD

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Bryan Barnes

SEMI Staff: Kevin Nguyen

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
<i>NIST</i>	<i>Barnes</i>	<i>Bryan</i>	<i>XYALIS</i>	<i>Morey</i>	<i>Philippe</i>
<i>Siemens</i>	<i>Gharat</i>	<i>Sayalee</i>	<i>XYALIS</i>	<i>Brault</i>	<i>Frederic</i>
<i>Mentor Graphics, Siemens</i>	<i>Kim</i>	<i>Stephen</i>	<i>Vistec Electron Beam</i>	<i>Weidenmueller</i>	<i>Ulf</i>
<i>HJL Lithography</i>	<i>Levinson</i>	<i>Harry</i>			

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>

Table 3 TC Chapter Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>TC Chapter Action</i>
7026	Reapproval of SEMI P44-1216, Specification For Open Artwork System Interchange Standard (OASIS®) Specific To Mask Tools	Passed as balloted
7027	Reapproval of SEMI P39-0416, Specification For OASIS® – Open Artwork System Interchange Standard	Failed

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Ratification Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>ISC A&R Action</i>	<i>A&R Forms</i>
None			



Table 6 Activities Approved by the GCS between meetings of the TC Chapter

#	Type	SC/TF/WG	Details
None			

Table 7 Authorized Activities

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

#	Type	SC/TF/WG	Details
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARE>

Table 8 Authorized Ballots

#	When	TF	Details
None			

Table 9 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
None			

Table 10 SNARF(s) Abolished

#	TF	Title
None		

Table 11 Standard(s) to receive Inactive Status

Standard Designation	Title
None	

Table 12 New Action Items

Item #	Assigned to	Details
October2023-#1	Philippe Morey (Xyalis)	To prepare the TFOF and SNARF for Revision of SEMI P39-0416, Specification For OASIS® – Open Artwork System Interchange Standard

Table 13 Previous Meeting Action Items

Item #	Assigned to	Details	Status
March2023-#1	Kevin Nguyen (SEMI)	To send doc.6821, New Preliminary Standard: Specification For Experimental Curvilinear “Multigon” Extension to SEMI P39 OASIS, to ISC for procedural review.	Completed



1 Welcome, Reminders, and Introductions

1.1 Bryan Barnes called the meeting to order at 9:00 AM. Before the meeting started, Bryan reminded all that there is an opening for a second co-chair. If anyone is interested, please inform him or SEMI staff.

1.2 The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

2.1 The TC Chapter reviewed the minutes of the previous meeting.

Motion: Accept the minutes as written

By / 2nd: Stephen Kim/ Harry Levinson

Discussion: None

Vote: 5-0. Motion passed.

Attachment: 01, Microlithography NA TC Minutes 03282023

3 SEMI Staff Report

3.1 Kevin Nguyen (SEMI) gave the SEMI Staff Report. Of note:

- SEMI upcoming event
 - SEMICON West, July 8-11, 2024
 - San Francisco, CA
- 2023 Critical Dates for SEMI Standards Ballots
 - <https://www.semi.org/en/collaborate/standards/ballots>
- New Publications Staff
 - Vivian Hoang – Sr. Specialist, Standards Publications
- SEMI Standards Publications
 - Total SEMI Standards in portfolio: 1,079
 - Includes 327 Inactive Standards
- Regulations and Procedure Manual Updates

Attachment: 02, Staff Report Nov 2023 v1

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 Doc.7026, Reapproval of SEMI P44-1216, Specification For Open Artwork System Interchange Standard (OASIS®) Specific To Mask Tools

4.1.1 This document **passed** the TC Chapter review as balloted. Refer to attachment below for full details.

Attachment: BallotReview7026



4.2 Doc. 7027, Reapproval of SEMI P39-0416, Specification For OASIS® – Open Artwork System Interchange Standard

4.2.1 Reject: Morey, Philippe (XYALIS)

4.2.1.1 Negative Text: Many issues leading to unpredictable results are still part of the standard.

4.2.1.2 Reason: More efficient compression methods should be added: standard offers the possibility to use multiple standards but only one is allowed

Motion: Negative is related and persuasive. (Needs > 1/3 votes to pass.)

By: Philippe Morey / Xyalis

Second: Frederic Brault / Xyalis

Result: 4-Y 0-N Voting Result: Pass - 100.00%

4.2.2 This document **failed** TC Chapter review.

5 Subcommittee and Task Force Reports

5.1 Curvilinear Format Task Force

5.1.1 Per the TF, Kevin reported no update for the MULTIGON document. The TF will present at the next meeting in Jan 2024 and will align with the EDA vendors.

5.2 Mask Orders P45 (MALY) Task Force

5.2.1 No report.

5.3 Patterning Metrology Task Force

5.3.1 Bryan Barnes reported no update.

5.4 P47 (Line-Edge Roughness) Revision Task Force

5.4.1 Harry Levinson reported Chris Mack provided the concept of the draft. Minor feedback was received. The TF will incorporate and discuss at the next meetings.

6 Old Business

6.1 Standards due for Five-Year Review.

None

6.2 SNARFs approaching 3-year Document Development Period

None

6.3 Previous Action Items

6.3.1 None

7 New Business

7.1 SEMI P39-0416, Specification For OASIS® – Open Artwork System Interchange Standard



7.1.1 Reapproval of SEMI P39 failed. Since P39 has no TF, Bryan Barnes inquired the members for the next step. Philippe Morey has made some suggestions on revision as he initially approached Thomas Grebinski, who was the author of P39, but received no responses.

7.1.2 Philippe Morey reported that he also raised revision proposal to the Curvilinear TF, but there was no interest.

7.1.3 Based on these circumstances, Philippe Morey believes it is best to form a new TF to focus on the SEMI P39 compression issue. Stephen Kim said since these are the same folks, he suggested this new proposal should be under the Curvilinear TF. Philippe responded and said it may be the same group of people, but the topic is different.

7.1.4 Kevin Nguyen suggested Philippe to fill out a new TFOF and SNARF to get this activity rolling. He can help with the administrative functions, but all the technical content should be up to the TF.

8 Next Meeting and Adjournment

8.1 The next TC Chapter meeting is to be determined.

Respectfully submitted by:

Kevin Nguyen,
SEMI Standards Operations Manager
Phone: 408-943-7997
Email: knguyen@semi.org

Minutes tentatively approved by:

Bryan Barnes (NIST) Co-chair	
------------------------------	--

Table 14 Index of Available Attachments^{#1}

<i>Title</i>	
Microlithography NA TC Minutes 03282023	
Staff Report Nov 2023 v1	
BallotReview7026	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Kevin Nguyen at the contact information above.